

326747-2026 - Result

Germany – Microelectronic machinery and apparatus – Fully Automated Wafer Cleaning Tool (IZM-130) - PR1097493-3460-P
OJ S 92/2026 13/05/2026
Contract or concession award notice – standard regime
Supplies

1. Buyer

1.1. Buyer

Official name: Fraunhofer-Gesellschaft - Einkauf B12
Email: einkauf@zv.fraunhofer.de
Legal type of the buyer: Public undertaking
Activity of the contracting authority: General public services

2. Procedure

2.1. Procedure

Title: Fully Automated Wafer Cleaning Tool (IZM-130) - PR1097493-3460-P
Description: Fully Automated Wafer Cleaning Tool (IZM-130)
Procedure identifier: 921b6280-68ce-4c6f-b4af-1a6f02706fc5
Internal identifier: PR1097493-3460-P
Type of procedure: Negotiated with prior publication of a call for competition / competitive with negotiation
The procedure is accelerated: no

2.1.1. Purpose

Main nature of the contract: Supplies
Main classification (cpv): 31712100 Microelectronic machinery and apparatus

2.1.2. Place of performance

Postal address: An der Bartlake 5
Town: Dresden
Postcode: 01109
Country subdivision (NUTS): Dresden, Kreisfreie Stadt (DED21)
Country: Germany
Additional information: Clean room - to be determined after contract award and consultation with Fhl

2.1.4. General information

Legal basis:
Directive 2014/24/EU
vgv -

5. Lot

5.1. Lot: LOT-0000

Title: Fully Automated Wafer Cleaning Tool (IZM-130) - PR1097493-3460-P

Description: 1x Fully Automated Wafer Cleaning Tool The following device specification defines a fully automated wet tool for cleaning and optional etching of wafer substrates. The new device expands the process portfolio with various cleaning technologies for removing organic and inorganic contaminants for applications such as cleaning TSVs with high aspect ratios (up to 25:1), front and back decontamination for ultra-high-density BEOL such as wiring or for stacking technologies with Cu/Cu hybrid connections with sub- μm structure sizes. The requirements for decontamination and cleanliness of the wafer surface necessitate particle control to less than 1 μm in size, metallic surface contamination of less than 10^9 atoms/cm², and surface roughness of less than 5 Å. The device is compatible with 3D wafer stacks with high deformation/warpage. The wafer substrates are made of silicon and/or glass, have a diameter of 200 or 300 mm and a thickness of up to 2.5 mm. Before the process, the wafers are transported to the device in front opening unified pods (FOUPs), which are manually placed on the respective loading openings by the operator. The new device must be capable of performing the following steps fully automatically: • Unloading the designated wafers from the FOUP • Turning the wafers • Performing the wet processes • Unloading the wafers back into their original position in the FOUP The programming of recipes must be possible within a reasonable range of options and parameters, as required for research and development (R&D). A safety cabinet must be available for mixing and storing all necessary wet chemicals. Optional features: - Thinned wafer thickness range of 200 and 300 mm (Si or glass): 300 ... 600 μm (LV item 1.19) - Extreme warpage and bow range 1500 .. 2500 μm (LV item 1.23) - Option: Inorganic etching process for metal and oxide layers (LV item 2.22) - Megasonic or similar energy as an option (LV item 2.58) - Single wafer spray process (LV item 2.59) - Adjustable spray nozzles/arm for optimising etching uniformity (LV item 2.60) - Optical end point detection (LV item 2.61) - Fast spin wafer chuck (adjustable) up to 2000 rpm (LV item 2.62) - Chemicals: two-component mixture and CO₂-charged DI water (LV item 2.63) - 10-litre internal tanks with single/recovery mode (LV item 2.64) - Overflow protection (LV item 2.65) - Safety cabinet for storage, mixing and refilling of the two components (LV item 2.66) - Pure DI water (LV item 2.67) - Dry process (LV item 2.68) - 10 x 300 mm wafer silicon oxide etching without residues (etching rate > 0.1 $\mu\text{m}/\text{min}$ for silicon dioxide, etching uniformity < 5 % 1 sigma) (LV item 3.25)

Internal identifier: LOT-0000

5.1.1. Purpose

Main nature of the contract: Supplies

Main classification (cpv): 31712100 Microelectronic machinery and apparatus

5.1.2. Place of performance

Postal address: An der Bartlake 5

Town: Dresden

Postcode: 01109

Country subdivision (NUTS): Dresden, Kreisfreie Stadt (DED21)

Country: Germany

Additional information: Clean room - to be determined after contract award and consultation with Fhl

5.1.3. Estimated duration

Start date: 05/07/2027

Duration end date: 09/07/2027

5.1.6. General information

Procurement Project fully or partially financed with EU Funds.

The procurement is covered by the Government Procurement Agreement (GPA): yes

5.1.7. Strategic procurement

Aim of strategic procurement: No strategic procurement

5.1.10. Award criteria

Criterion:

Type: Quality

Name: Technical Specification

Description: Technical Specification

Category of award weight criterion: Weight (percentage, exact)

Award criterion number: 65

Criterion:

Type: Price

Name: Price

Description: Price

Category of award weight criterion: Weight (percentage, exact)

Award criterion number: 35

5.1.15. Techniques

Framework agreement:

No framework agreement

Information about the dynamic purchasing system:

No dynamic purchase system

5.1.16. Further information, mediation and review

Review organisation: Vergabekammern des Bundes

Organisation providing additional information about the procurement procedure: Fraunhofer-Gesellschaft - Einkauf B12

Organisation providing more information on the review procedures: Fraunhofer-Gesellschaft zur Förderung der angewandten Forschung e.V.

6. Results

Value of all contracts awarded in this notice: unpublished

Justification code: Law enforcement

6.1. Result lot identifier: LOT-0000

Winner selection status: At least one winner was chosen.

6.1.2. Information about winners

Winner:

Official name: Veeco GmbH

Tender:

Tender identifier: TEN-0001

Identifier of lot or group of lots: LOT-0000

Value of the tender: unpublished

Justification code: Law enforcement

Subcontracting: No

Contract information:

Identifier of the contract: CON-0001

Date of the conclusion of the contract: 12/05/2026

6.1.4. Statistical information

Received tenders or requests to participate:

Type of received submissions: Tenders

Number of tenders or requests to participate received: 2

Type of received submissions: Tenders submitted electronically

Number of tenders or requests to participate received: 2

Type of received submissions: Tenders from micro, small or medium tenderers

Number of tenders or requests to participate received: 1

Type of received submissions: Tenders from tenderers registered in other European Economic Area countries than the country of the buyer

Number of tenders or requests to participate received: 0

Type of received submissions: Tenders from tenderers registered in countries outside of the European Economic Area

Number of tenders or requests to participate received: 0

8. Organisations

8.1. ORG-7001

Official name: Fraunhofer-Gesellschaft - Einkauf B12

Registration number: DE 129515865

Postal address: Hansastrasse 27c

Town: München

Postcode: 80686

Country subdivision (NUTS): München, Kreisfreie Stadt (DE212)

Country: Germany

Contact point: Einkauf Betrieb und Infrastruktur

Email: einkauf@zv.fraunhofer.de

Telephone: +49891205-0

Internet address: <https://vergabe.fraunhofer.de/>

Buyer profile: <https://vergabe.fraunhofer.de/NetServer/>

Roles of this organisation:

Buyer

Central purchasing body awarding public contracts or concluding framework agreements for works, supplies or services intended for other buyers

Organisation providing additional information about the procurement procedure

8.1. ORG-7004

Official name: Vergabekammern des Bundes

Registration number: t:022894990

Postal address: Kaiser-Friedrich-Straße 16

Town: Bonn

Postcode: 53113

Country subdivision (NUTS): Bonn, Kreisfreie Stadt (DEA22)

Country: Germany

Email: vk@bundeskartellamt.bund.de

Telephone: +49 228 9499-0

Roles of this organisation:

Review organisation

8.1. ORG-7005

Official name: Fraunhofer-Gesellschaft zur Förderung der angewandten Forschung e.V.
Registration number: DE-129515865
Postal address: Hansastrasse 27c
Town: München
Postcode: 80686
Country subdivision (NUTS): München, Kreisfreie Stadt (DE212)
Country: Germany
Email: einkauf@zv.fraunhofer.de
Telephone: +49 89 1205-0
Internet address: <https://www.fraunhofer.de>

Roles of this organisation:

Organisation providing more information on the review procedures

8.1. ORG-0001

Official name: Veeco GmbH
Size of the economic operator: Large
Registration number: DE258288047
Postal address: Einsteinring 22
Town: Aschheim
Postcode: 85609
Country subdivision (NUTS): München, Landkreis (DE21H)
Country: Germany
Email: jgessler@veeco.com
Telephone: +49 1746835876

Roles of this organisation:

Tenderer

Beneficial owner:

Winner of these lots: LOT-0000

8.1. ORG-7006

Official name: Datenservice Öffentlicher Einkauf (in Verantwortung des Beschaffungsamts des BMI)
Registration number: 0204:994-DOEVD-83
Town: Bonn
Postcode: 53119
Country subdivision (NUTS): Bonn, Kreisfreie Stadt (DEA22)
Country: Germany
Email: noreply.esender_hub@bescha.bund.de
Telephone: +49228996100

Roles of this organisation:

TED eSender

Notice information

Notice identifier/version: f2568516-360b-4ef0-be5e-03c350ccc4bb - 01

Form type: Result

Notice type: Contract or concession award notice – standard regime

Notice subtype: 29

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